

Session Title:	[Tu1E] Dimensional Metrology III
Session Date:	August 6 (Tue.), 2024
Session Time:	11:00-12:30
Session Room:	Room E (114)
Session Chair(s)	Dr. Jonghan Jin (KRISS, Korea), Dr. Kiso Kim (KOPTI, Korea)

[Tu1E-1] [Invited] 11:00-11:30

Double-sided Interferometer for SI-traceable Thickness Measurement

Akiko Hirai and Youichi Bitou (Nat'l Metrology Inst. of Japan, Japan)

[Tu1E-2] 11:30-11:45

Application for Wafer Measurement using Multi-channel Laser Ranging based on Dual-comb Time-of-flight with High-efficiency Cross-correlation via Semiconductor Optical Amplifier

Jaeyoung Jang, Hyeokin Kang, Hyunsu Kim, Seung-Woo Kim, and Young-Jin Kim (KAIST, Korea)

[Tu1E-3] 11:45-12:00

Measurement of Temporal Phase of Weak Optical Pulses in a Noisy Environment

Jerzy Szuniewicz (Univ. of Warsaw, Poland), Steven Sagona-Stophel, Sarah Thomas, Ian Walmsley (Imperial College London, UK), and Michał Karpiński (Univ. of Warsaw, Poland)

[Tu1E-4] 12:00-12:15

Phase Noise Measurement with Delay Interferometer During Fast Polarization Fluctuation

Shiro Ryu (Meiji Univ., Japan)

[Tu1E-5] 12:15-12:30

Precise Enhancement for Optical Delay Measurement

Haoxuan Zhang, Weimeng Wang, Song Yu, Bin Luo, and Tianwei Jiang (Beijing Univ. of Posts and Telecommunications, China)